Notice of Allowability	Application No.	Application No. Applicant(s)	
	10/604,857	604,857 LIU, YU-CHENG	
	Examiner	Art Unit	
	Mary Wilczewski	2822	A-w
The MAILING DATE of this communication ap All claims being allowable, PROSECUTION ON THE MERITS herewith (or previously mailed), a Notice of Allowance (PTOL-8 NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT of the Office or upon petition by the applicant. See 37 CFR 1.3	IS (OR REMAINS) CLOSED in 35) or other appropriate communities. This application is su	this application. If not include nication will be mailed in due of	d course. THIS
1. X This communication is responsive to the Response to F	Restriction Requirement filed 09	<u>April 2004</u> .	
2. The allowed claim(s) is/are <u>1-4</u> .			
3. The drawings filed on <u>22 August 2003</u> are accepted by	the Examiner.	<u></u>	
 4. Acknowledgment is made of a claim for foreign priority a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 		r (f).	
2. Certified copies of the priority documents have		No.	j
3. Copies of the certified copies of the priority	• •		ion from the
	documents have been received	in this national stage applicat	ion nom the
International Bureau (PCT Rule 17.2(a)). * Certified copies not received:			
Applicant has THREE MONTHS FROM THE "MAILING DAT noted below. Failure to timely comply will result in ABANDOI THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.		a reply complying with the req	uirements
5. A SUBSTITUTE OATH OR DECLARATION must be sul INFORMAL PATENT APPLICATION (PTO-152) which g			OTICE OF
6. CORRECTED DRAWINGS (as "replacement sheets") n		(DTO 040) att = 1	
(a) including changes required by the Notice of Draftsp	•	(PIO-948) attached	
1) hereto or 2) to Paper No./Mail Date		. A. O.C	
(b) ☐ including changes required by the attached Examin Paper No./Mail Date	er's Amendment / Comment or i	n the Office action of	
Identifying indicia such as the application number (see 37 CFI each sheet. Replacement sheet(s) should be labeled as such i			back) of
7. DEPOSIT OF and/or INFORMATION about the de attached Examiner's comment regarding REQUIREMEN	•		ote the
Attachment(s)			
I. ☑ Notice of References Cited (PTO-892)		ormal Patent Application (PTC)-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948	Paper No./N	/lail Date	
Information Disclosure Statements (PTO-1449 or PTO/SI Paper No./Mail Date	<u>_</u>	mendment/Comment	
1. Examiner's Comment Regarding Requirement for Deposit		Statement of Reasons for Allow	wance
of Biological Material	9. Other		_
		M. Wilczewski Primary Examiner Tech Center 2800	

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EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

The application has been amended as follows:

This application is in condition for allowance except for the presence of claims 5-15 drawn to an invention non-elected without traverse in the Response to Restriction Requirement filed on April 9, 2004. Accordingly, claims 5-15 have been cancelled.

Statement of Reasons for Allowance

The following is an examiner's statement of reasons for allowance: The prior art is replete with sputtering apparatuses that have means for heating and/or cooling various parts of the apparatus, for example, the heating and/or cooling of substrate supports (see, for example, U.S. Patent 5,892,207 or U.S. Patent 5,478,609), the cooling of target supporting members (U.S. Patent 5,328,585), the temperature monitoring and heating of a processing chamber (U.S. Patent Publication US2001/0042594) and the cooling of a magneton sputtering apparatus by flowing a coolant through a hollow drive shaft coupled to the magnetron (U.S. Patent 6,641,701). The prior art also discloses apparatuses

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that include inner chambers within a larger outer chamber, these inner chambers having heating and/or cooling means (U.S. Patent 6,270,633 and U.S. Patent 6,015,594). In addition, U.S. Patent 4,339,326 discloses an apparatus that comprises a cooling pipe (21) provided on the outer wall off the processing chamber (5) in order to cool the chamber from the outside by running cooling water through the pipe. However, none of the prior art of record teaches or suggests a sputtering apparatus comprising a cathode on which a target is installed which has a temperature-controlling device comprising a temperature sensor installed on an inner sidewall of the chamber for measuring the temperature of the inner sidewall of the chamber and a temperature receiver connected to the temperature sensor, for receiving and storing temperature data measurements and a water-cooling system comprising cooling-water piping encircling sidewalls of the chamber wherein the flow rate of the cooling water is controlled based on temperature signals from the temperature receiver, thereby controlling the temperature of the inner sidewall.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

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Any inquiry concerning this communication should be directed to M.

Wilczewski at telephone number (571) 272-1849.

M. Wilczewski Primary Examiner Tech Center 2800